

RECEIVED
CENTRAL FAX CENTER

SEP 20 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

App. No. : 10/065,552 Confirmation No. 7687
Applicant : Shigeru Sawada
Filed : October 29, 2002
Tech. Cntr./Art Unit : 2814
Examiner : Louie Wai Sing

Docket No. : 39,002-AG
Customer No. : 29453

I hereby certify that this correspondence is
being facsimile-transmitted to the
U.S. Patent and Trademark Office,
fax no. (703) 872-9306 on Sept. 20, 2004.

James W. Judge
Reg. No. 42,701

Signature

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313 1450

REPLY Under 37 C.F.R. § 1.111

Sir:

In response to the Office action of August 18, 2004 Applicant hereby
provisionally elects, with traverse, Group I.

REMARKS

On the grounds that the subject matter of claims 8-13, which depend from
method claims 1-6 respectively, is inseparably dependent on the subject matter of
claims 1-6, Applicant respectfully traverses the holding that claims 8-13 are drawn to
a distinct invention.

Claims 8-13 are directed to compound semiconductor wafers having the novel
property of being usable as-is despite having had their carrier concentrations profiled.
The Office action quotes MPEP § 806.05(f) as stating that a process of making and
the product made are patentably distinct if it can be shown that "the product as
claimed can be made by another and materially different process." (Emphasis is the
MPEP's.)

Although in the Office action it is suggested that "instead of using a C/V
technique to profile the compound semiconductor wafer, it would be possible to use
an electron beam to profile the compound semiconductor wafer," the Office action
has not expressly set forth how such a substitution would produce the product as